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**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hideki SATO

Application No.: New U.S. Patent Application

Filed: September 26, 2006

Docket No.: 129546

For: METHOD FOR EVALUATING CRYSTAL DEFECTS OF SILICON WAFER

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Please consider the following:

**Amendments to the Specification;**

**Amendments to the Claims** as reflected in the listing of claims;

**Remarks.**